

IFW

PATENT
8074-1143

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Koichi NANIWAE

Conf. unknown

Application No. 10/573,492

Group unknown

Filed March 24, 2006

Examiner unknown

METHOD OF CLEANING TREATMENT AND METHOD
FOR MANUFACTURING SEMICONDUCTOR DEVICESUPPLEMENTAL INFORMATION DISCLOSURE STATEMENTCommissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

June 27, 2006

Sir:

In compliance with Rules 1.97 and 1.98, and in fulfillment of the duty of disclosure under Rule 1.56, the accompanying document, a copy of which is attached to this statement, is made of record on the enclosed sheet.

A concise explanation of the relevance of this item is that this reference is discussed on pages 3 and 4 of the present specification.

Respectfully submitted,

YOUNG & THOMPSON

Robert J. Patch, Reg. No. 17,355
745 South 23rd Street
Arlington, VA 22202
Telephone (703) 521-2297
Telefax (703) 685-0573
(703) 979-4709

RJP/fb

(Use several sheets if necessary)

8074-1143

10/573,492

Koichi NANIWAE

March 24, 2006

unknown

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER:

/Eric Jones/

DATE CONSIDERED

8/20/2008

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

* Abstract provided for the Examiner's convenience